

***Noise coupling
due to scattered light
from output optics***

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Contents of the talk

- Brief introduction of simulation activities in TAMA/LCGT collaborations

- Scattered light noise

Motivation

Principle of the noise

Approach used in this study

Simulation and interpretation of the result

Michelson/Recycled MI/Recycled FPMI

Discussion/Conclusion

Simulation activities in TAMA/LCGT

- No comprehensive work to construct our own simulation environment / tool
- As users of the simulation softwares
 - E2E:** (ICRR - Hayakawa, et al, with LIGO E2E team)
Modeling of CLIO (100-m cryogenic prototype in Kamioka)
 $h(t)$ injection module
 - Finesse:** (NAOJ - Kawamura, et al with LIGO 40m team)
Lock acquisition study for Caltech 40m
Sensing design for an RSE interferometer (NAOJ - Kokeyama, et al)
Scattered light noise estimation (NAOJ - Arai, et al)
 - LISO:**
Linear circuit simulations (NAOJ, U-Tokyo. etc)
- Analysis related simulations
 - Software signal injection of galactic GW events**
 - Crosstalk study of two co-located interferometer**
(Osaka City Univ - Kanda, et al)

Scattered light ~ introduction

- Demand of simulations from the site

Commissioning work

- > Various kind of problems day by day
- > Always confused by the complicated "real world"

To grasp what is happening in the real detector

- > Even a simple model is often sufficient
 - if it reflects the physics we want.
- > No need to be too exact
 - actual values will be obtained from experiments

Feedback to experiments

- > Suggestions to the experiment
- > Suggestions of experimental methods

Scattered light \sim motivation

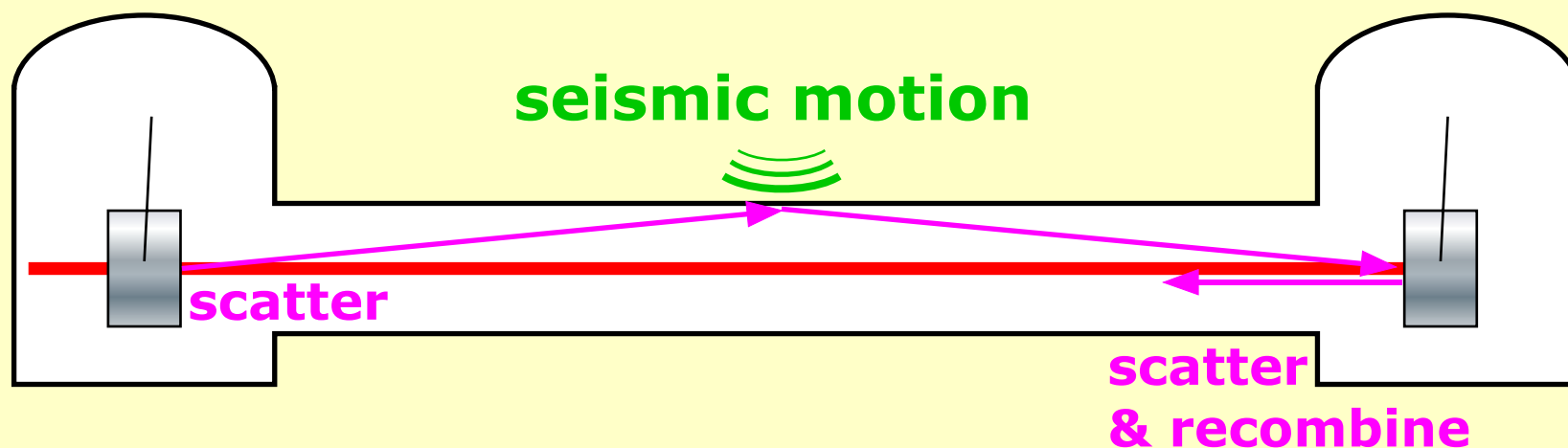
- Scattered light noise

A) Scattered light in the beam tube

B) Scattered light at the optical ports

A) Scattered light in the beam tube

> For the design of the long vacuum tubes and the baffles



> Experiment in TAMA

Excitation of a tube resonance: 5.6 μ m@ 776.5Hz \Rightarrow 1x10⁻¹⁷ m in the sensitivity

i.e. Seismic motion $dx =$ 1x10⁻⁷ / f² m/sqrtHz \Rightarrow \sim 2 x 10⁻¹⁹ / f² m/sqrtHz

\Rightarrow Negligible

Scattered light ~ motivation

B) Scattered light at the optical ports

Fact: touching of the output optics
=> mechanical peaks in the sensitivity

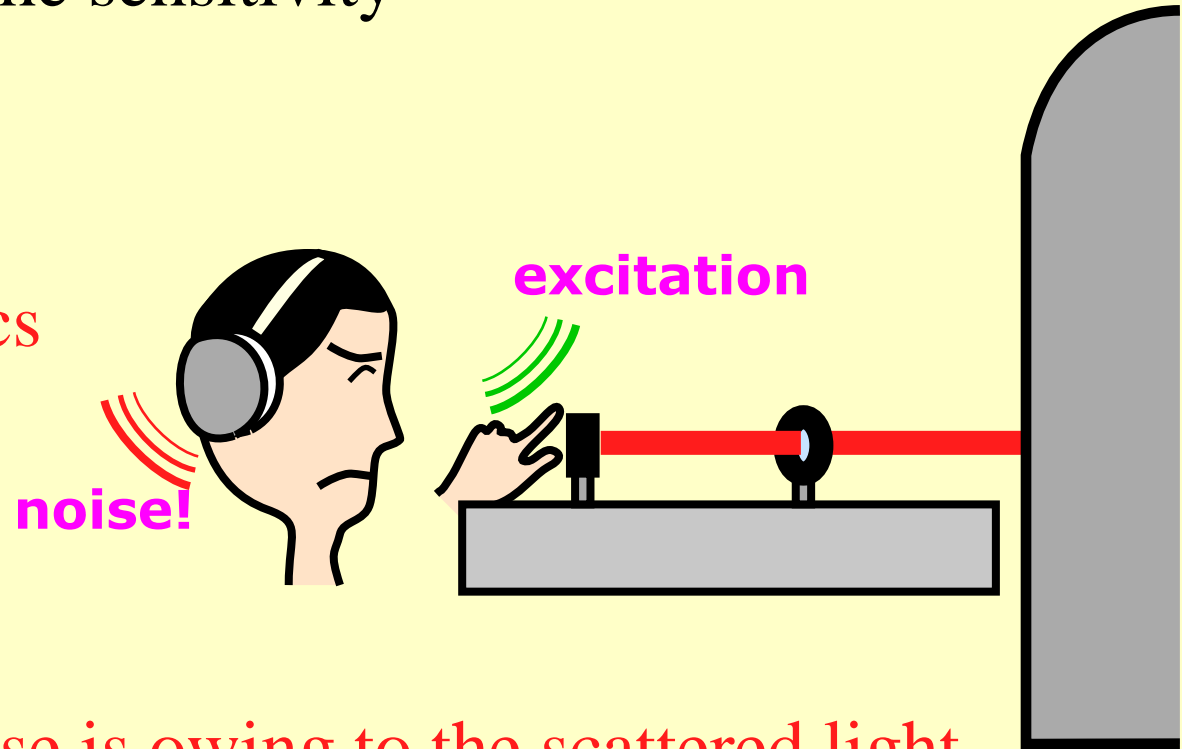
e.g.

> Tapping of the dark port optics

=> huge noise

> Bright port

=> moderate noise



Expect some fraction of the noise is owing to the scattered light

Q. Which optical port is dangerous? How much?

> Tapping every optics

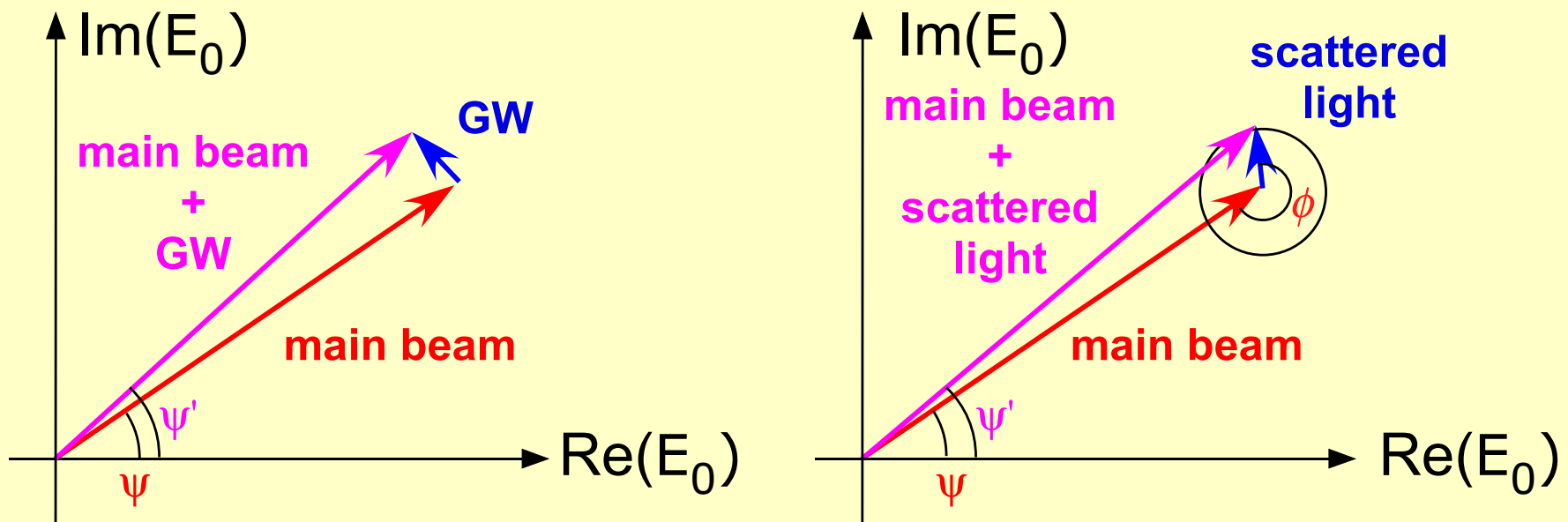
> More systematic estimation?

Scattered light \sim principle

- Coupling of scattered light to the output signal

GW detector = optical phase sensor

Electric field of the main beam $E = E_0 e^{i \Omega t}$



Scattered light recombined to the main beam

Motion of the scattering body

\Rightarrow perturbation of the optical phase

\Rightarrow Appear in the output signal

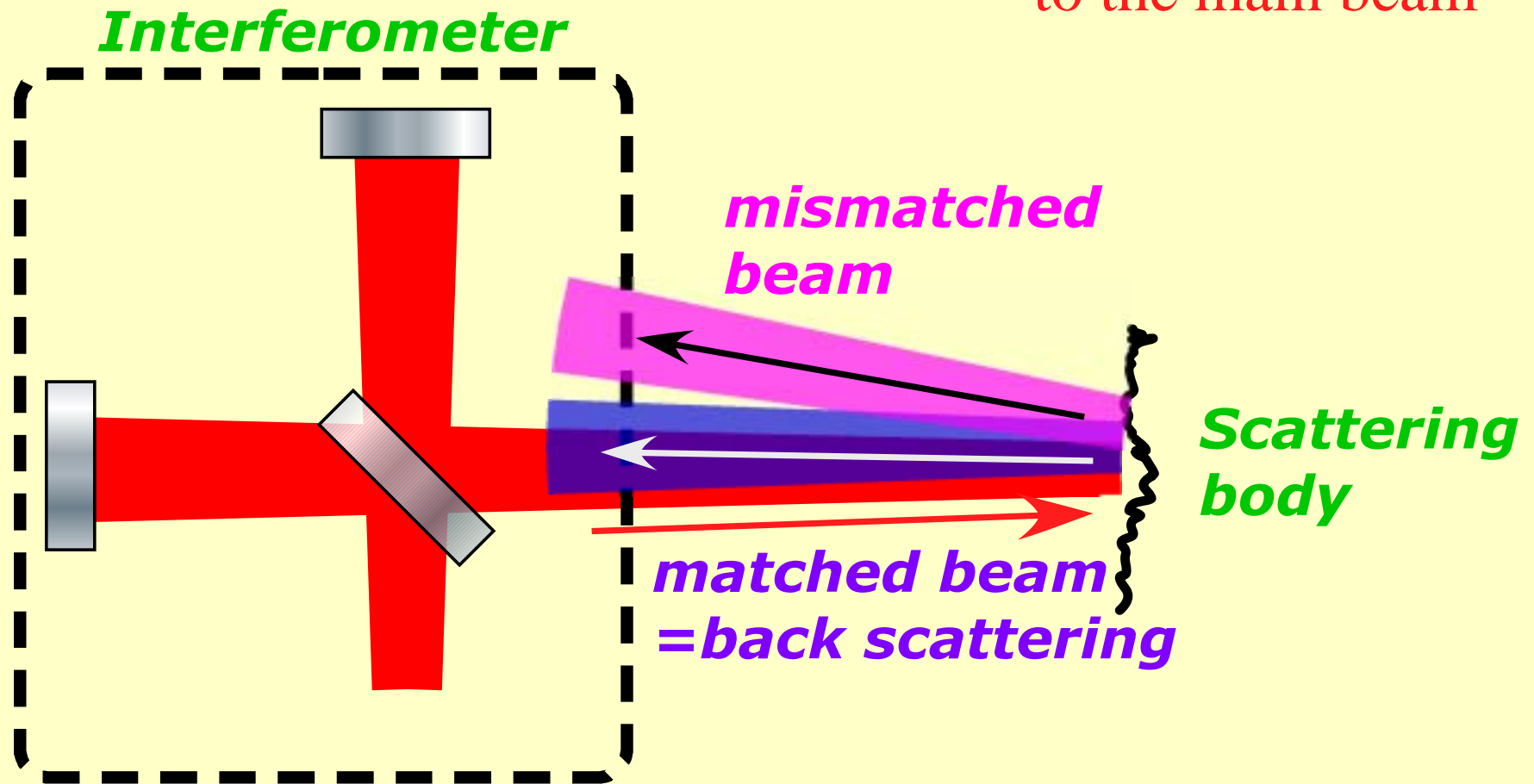
Scattered light \sim back scattering

- Only back scattering is considered

In order to couple to the output signal

\Rightarrow The scattered light should be spatially matched

to the main beam

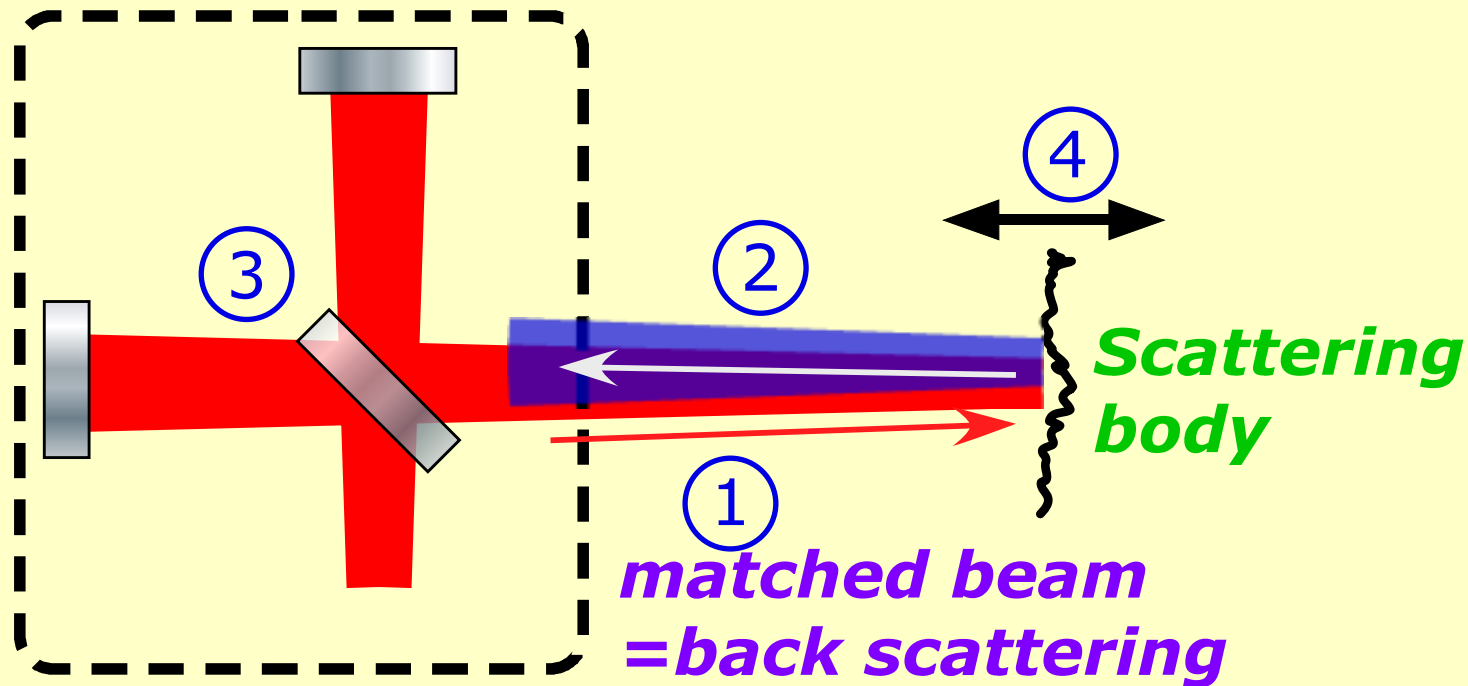


\Rightarrow Only consideration of TEM₀₀ is enough

Scattered light \sim factors

- Factors to determine the amount of the noise

Interferometer



1. Amount of the light power arrives on the scattering body.
2. Efficiency of effective back scattering
3. Sensitivity of the signal to the scattering
4. Amount of the scattering body's motion

$$P_{\text{out}}$$

$$\eta_{\text{scat}}$$

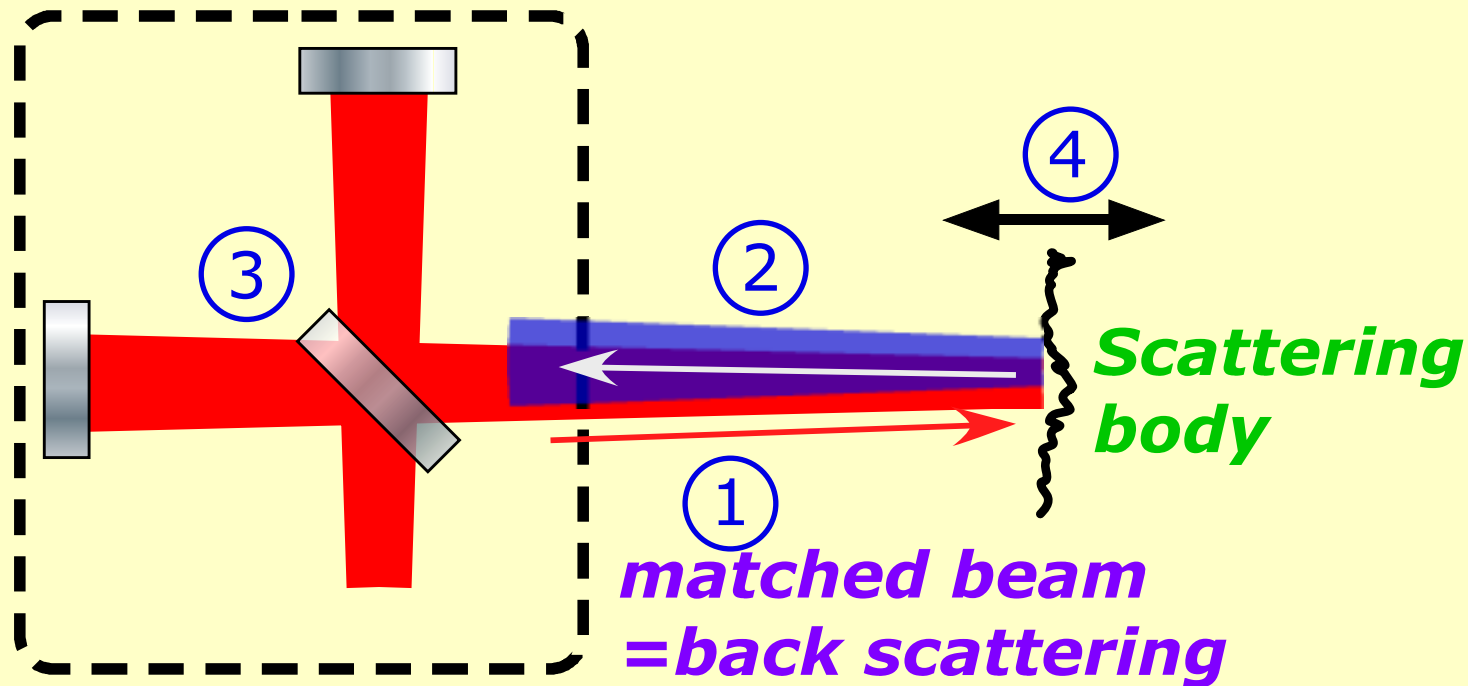
$$\alpha$$

$$\delta x_{\text{scat}}$$

Scattered light \sim factors

- Factors to determine the amount of the noise

Interferometer



1. Amount of the light power arrives on the scattering body. \Rightarrow **Easy to simulate**
2. Efficiency of effective back scattering \Rightarrow **Experiment**
3. Sensitivity of the signal to the scattering \Rightarrow **Easy to simulate**
4. Amount of the scattering body's motion \Rightarrow **Experiment**

Simulation ~ Using Finesse

- "Finesse" is selected for the tool
Reason: It looked the easiest tool for the purpose
Any kind of length sensing tool does fit
- Use Finesse at the most basic level
Modulation sideband: up to 1st order
Spatial mode: only TEM₀₀
Frequency range: only at DC
- Based on the TAMA300 parameters
Michelson (MI) / Recycled Michelson (RMI) model
=> To understand nature of the scattered light noise

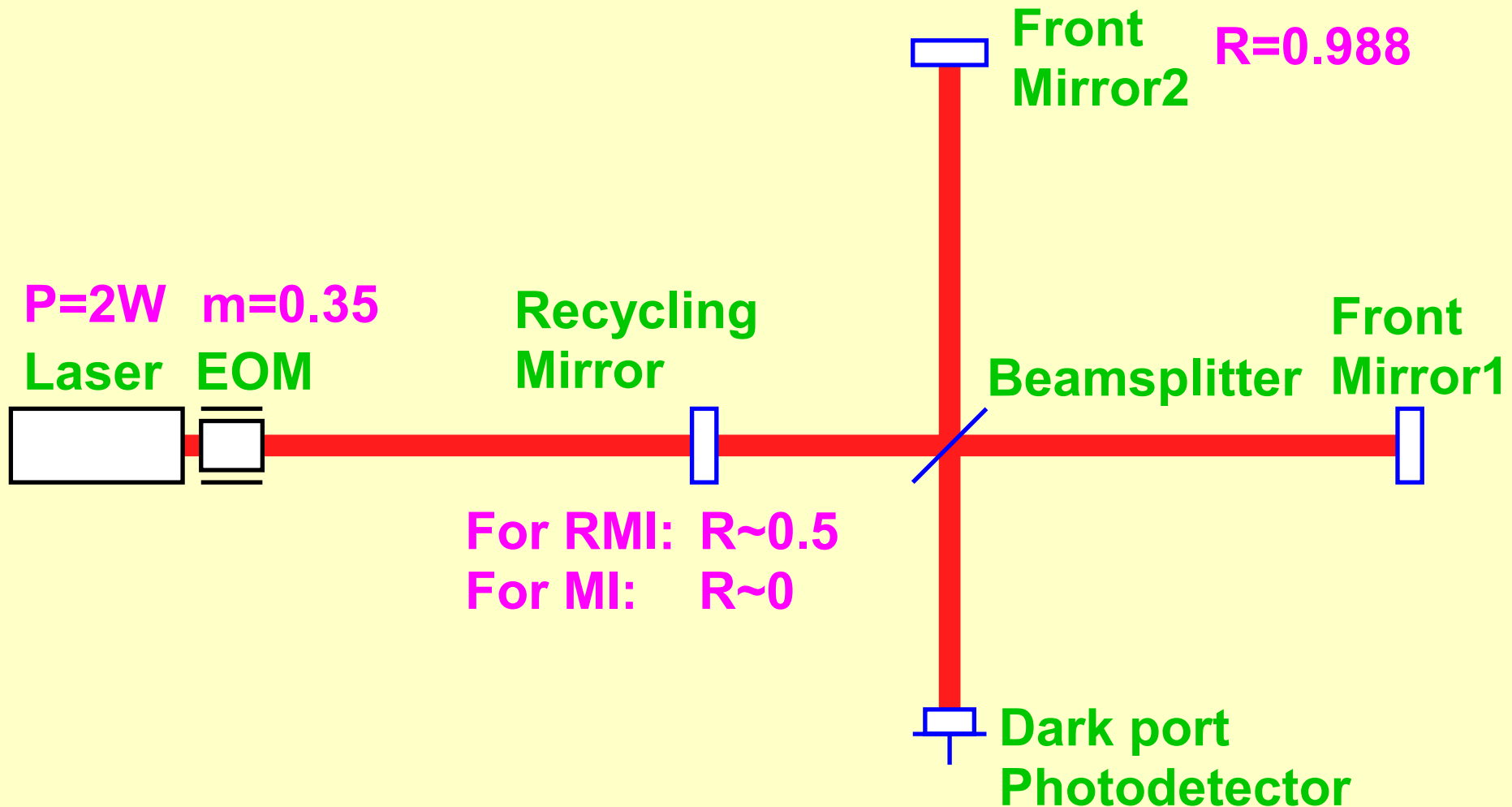
Recycled Fabry-Perot Michelson (RFPMI) model
=> To acquire the applicable knowledge to TAMA300

Simulation \sim MI/RMI model

RMI:

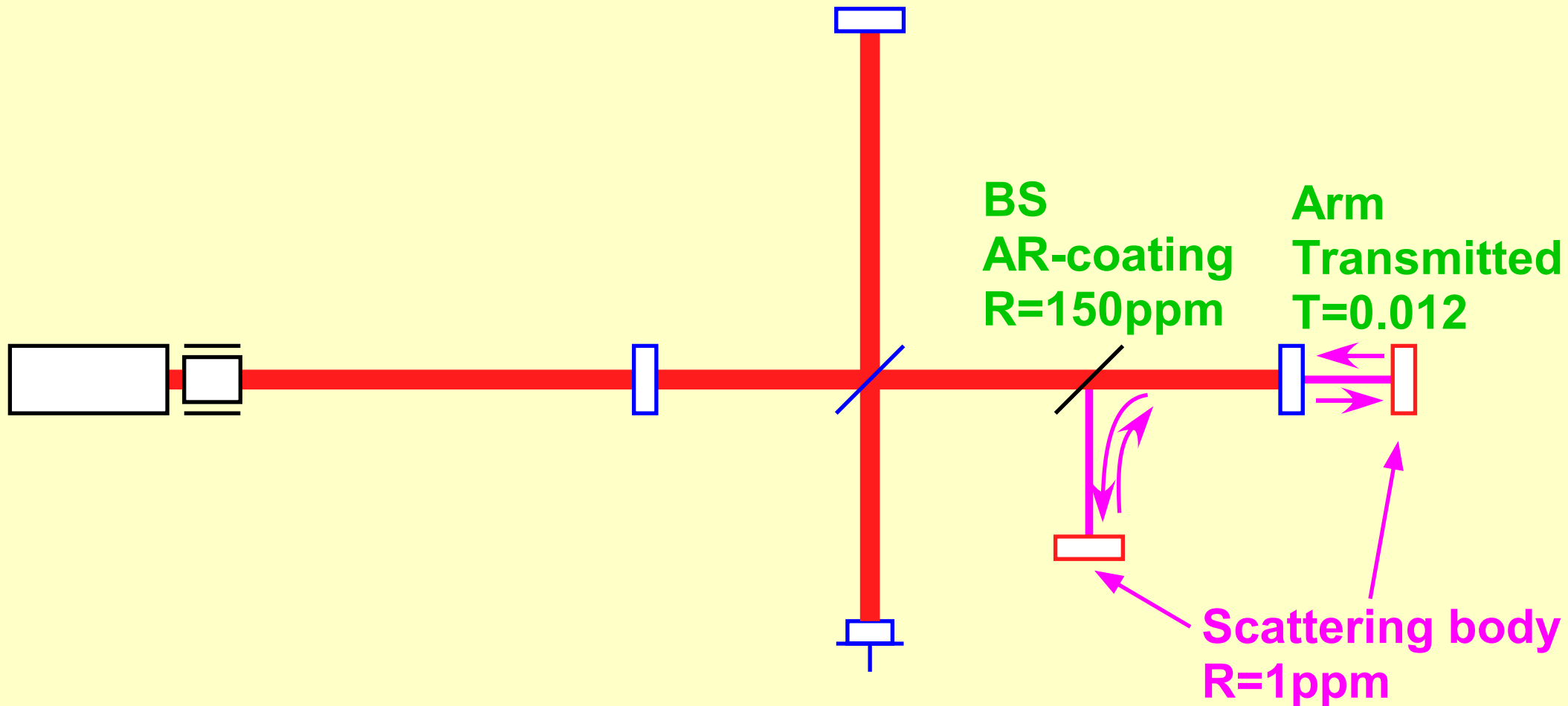
The carrier is resonant

The sidebands are not resonant



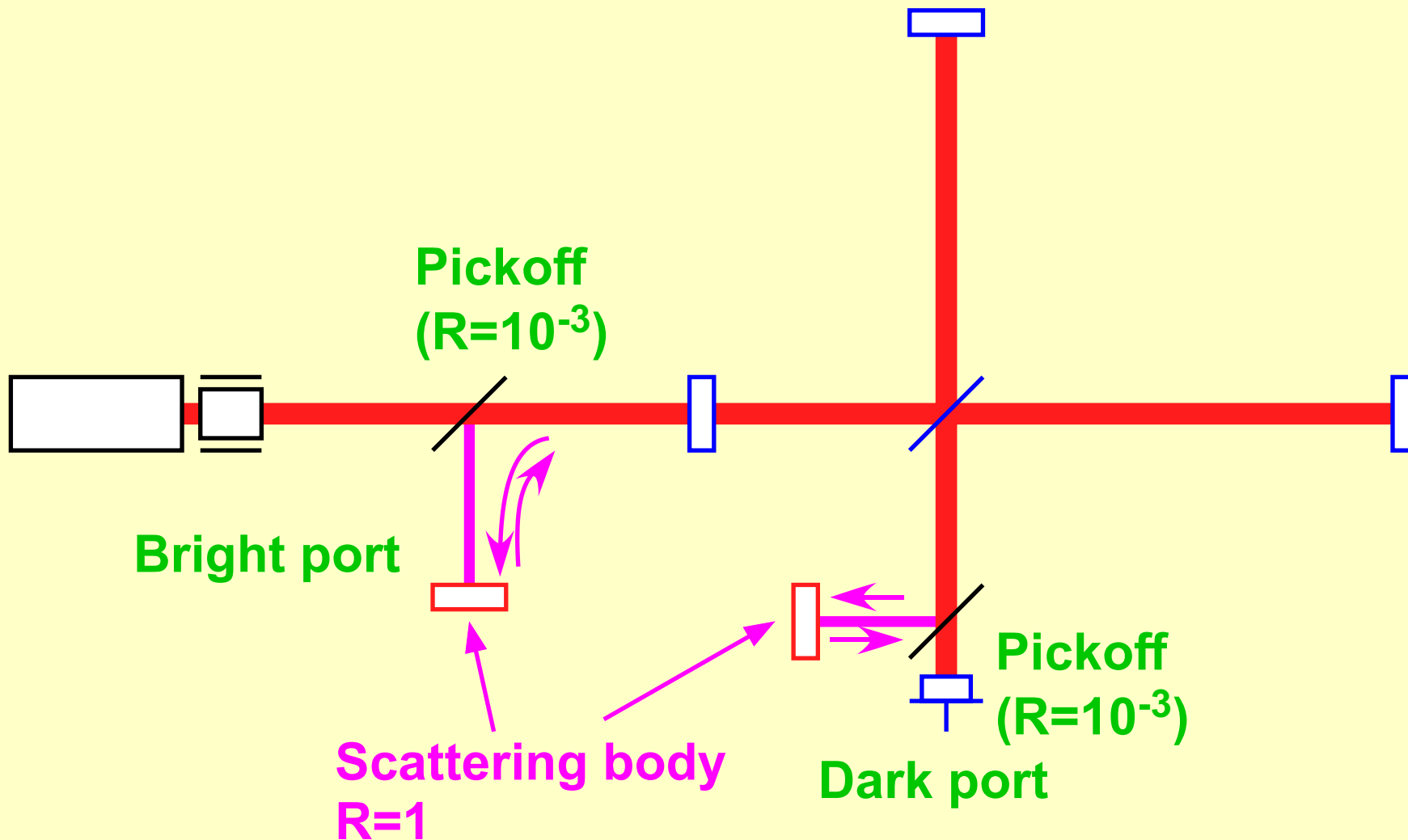
Simulation ~ MI/RMI model

Placing scattering bodies
with effective reflectivity of 1ppm



Simulation ~ MI/RMI model

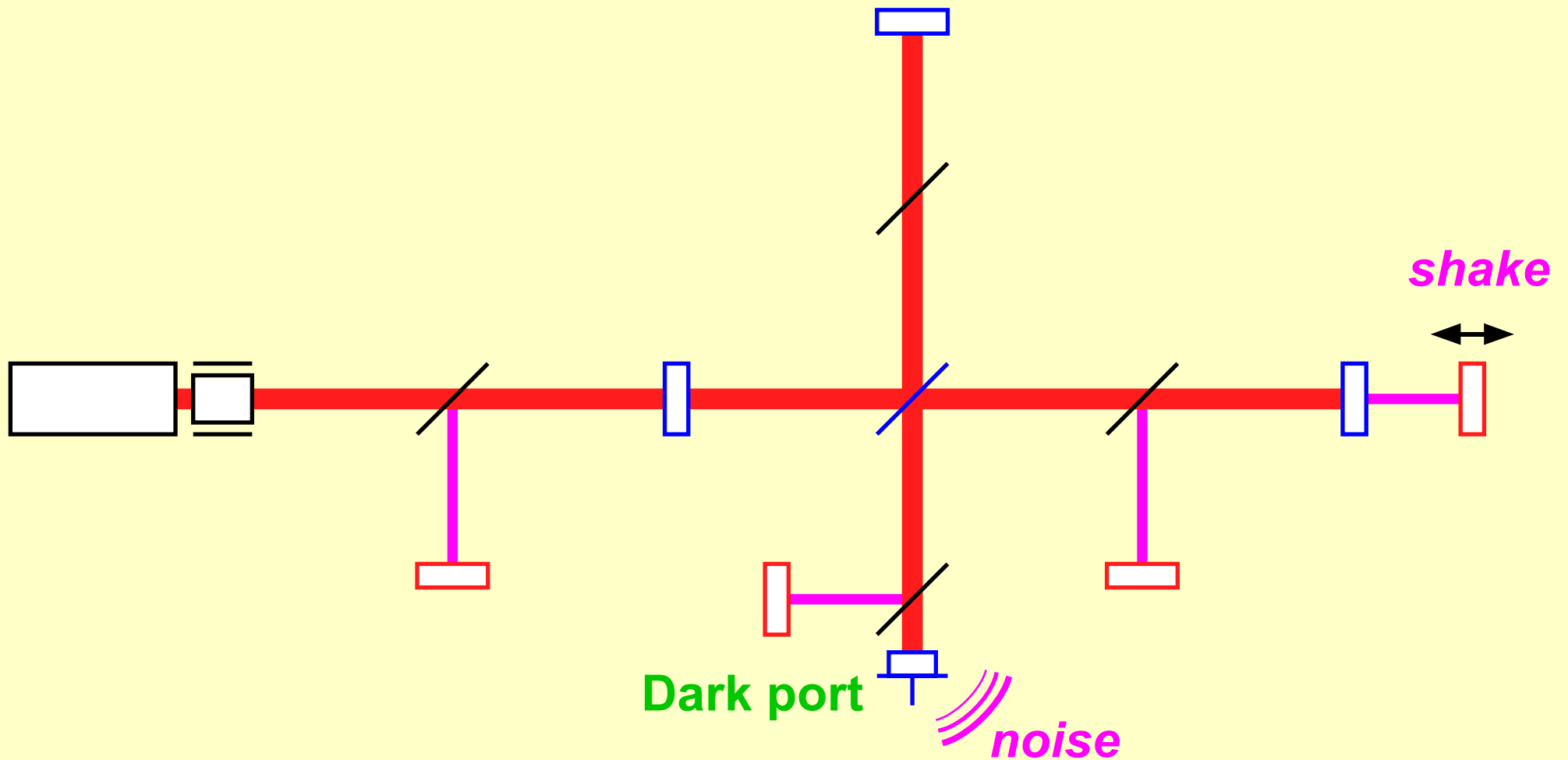
Pickoff mirrors ($R=10^{-3}$) are inserted at several places
~ avoiding to disturb the internal condition



Simulation ~ MI/RMI model

Sweep the position of each scattering body

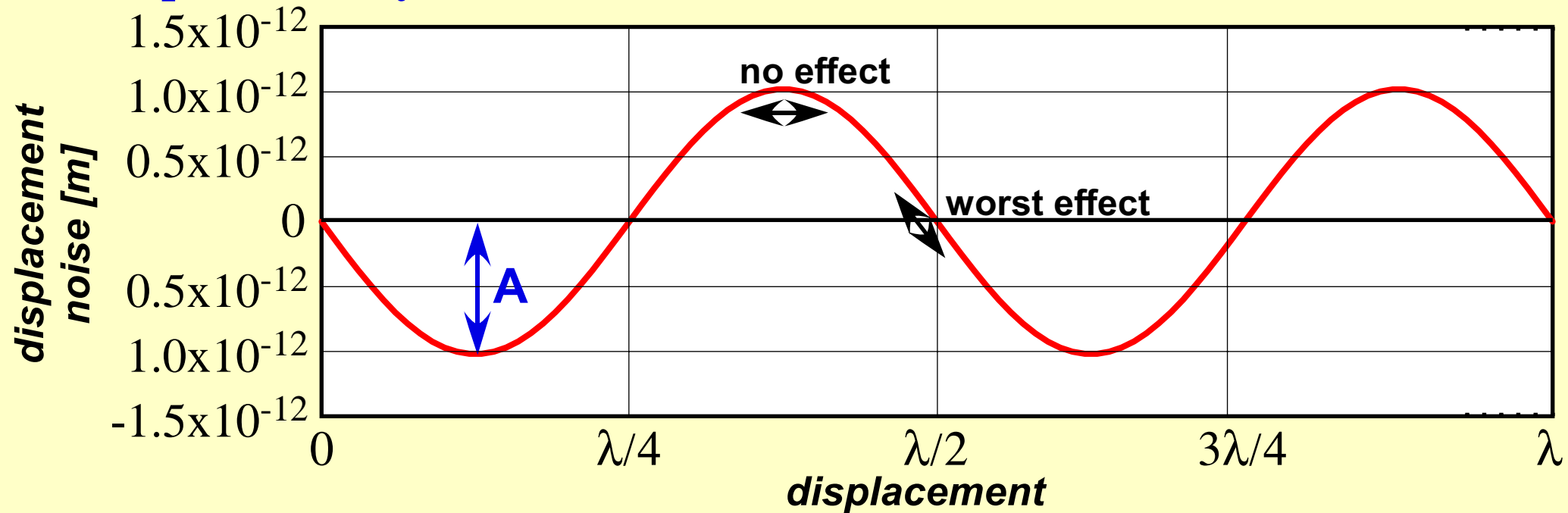
=> Look at the dark port signal



Simulation ~ how to evaluate the result

● Effect of the motion of the scattering source

Example: noise by the motion of the mirror behind the arm



> **Small amplitude motion**

$$\delta x_{\max} = (4 \pi A / \lambda) \delta x_{\text{scat}}$$

> **Large amplitude motion**

$$dx = A \quad \text{at } f = 2 \nu_{\text{scat}} / \lambda \quad (\text{fringe frequency})$$

> **Note:** Noise amplitude A is proportional

to the “amplitude” of the scattered light

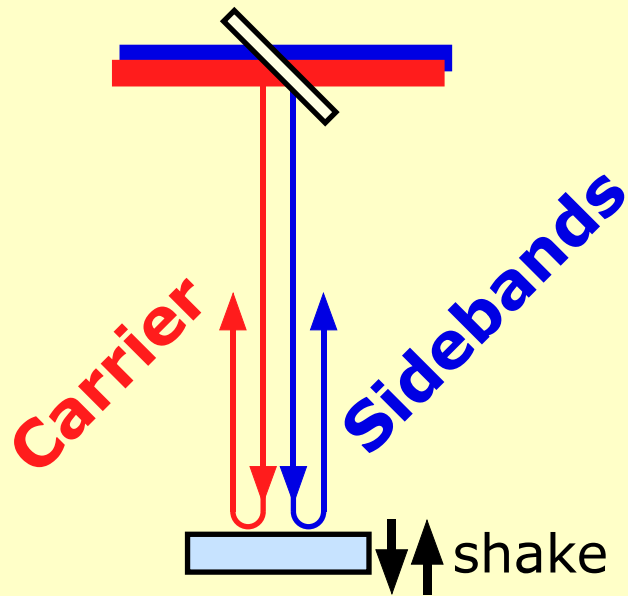
$$R_{\text{scat}} = 1 \text{ ppm} \Rightarrow A$$

$$R_{\text{scat}} = 100 \text{ ppm} \Rightarrow A' = 10 A$$

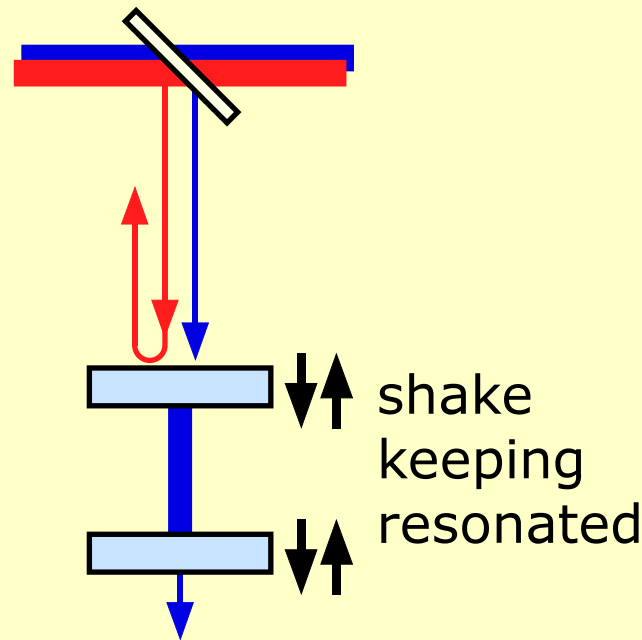
Simulation ~ Carrier/sideband decomposition

● Scattering source ~ three kinds of “mirrors”

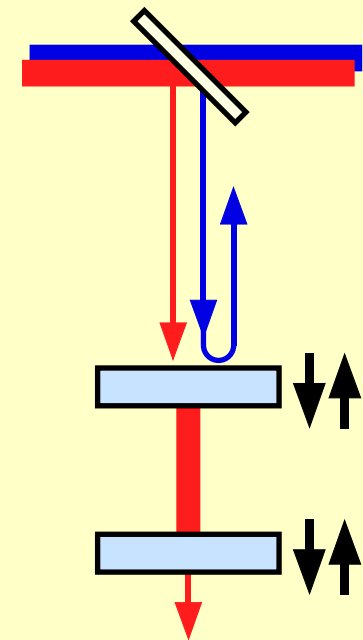
> Separating the contribution of the carrier and the modulation sidebands



Mirror:
CA reflected
SB reflected



SB resonant FP:
CA reflected
SB absorbed



CA resonant FP:
CA absorbed
SB reflected

(reflection 99.7%, absorption ~100%)

Simulation method summary

- Sweep the position of each scattering source
Scattering source at: Arm trans., BS AR coat, Dark, Bright
Detector output: Sin wave (amplitude A)
 $\Rightarrow A = (P_{\text{out}})^{\epsilon} \propto \eta_{\text{scat}}$ for $\eta_{\text{scat}} = 1$ ppm
- Decompose the contribution of CA/SB
Ordinary mirror: Carrier + Sidebands
SB resonant FP: only Carrier
CA resonant FP: only Sidebands
- Inject imperfections of the interferometer
Michelson offset: $dx = 10^{-12} \text{ m} \sim 10^{-10} \text{ m}$
Reflectivity mismatch of the arm mirrors:
 $dR = 100 \text{ ppm} \sim 10000 \text{ ppm}$
Note: Macro- and microscopic deviations of the recycling cavity hardly effect the results

MI/RMI model \sim DC power

RMI case:

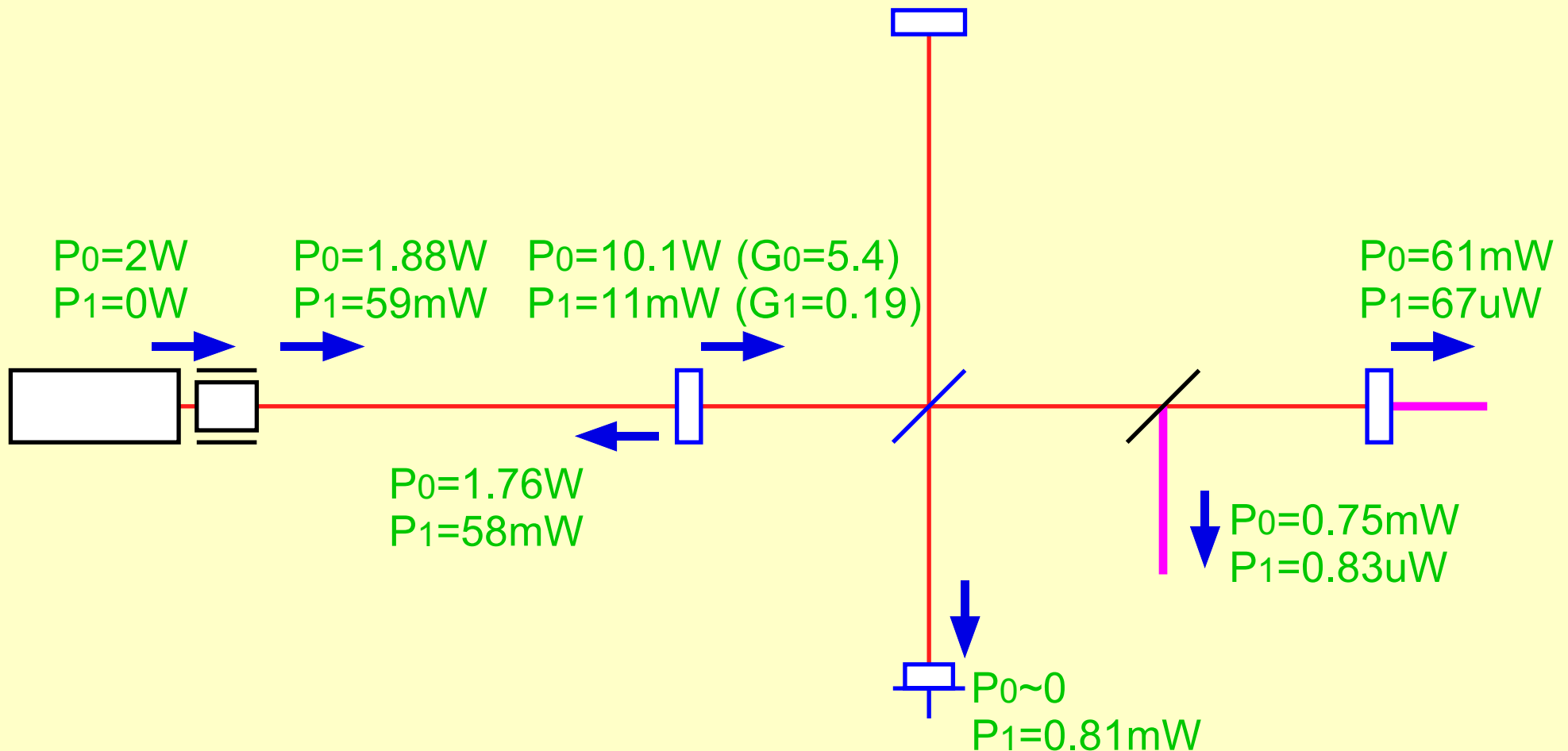
P_0 : carrier power

P_1 : sideband power

Power consumption:

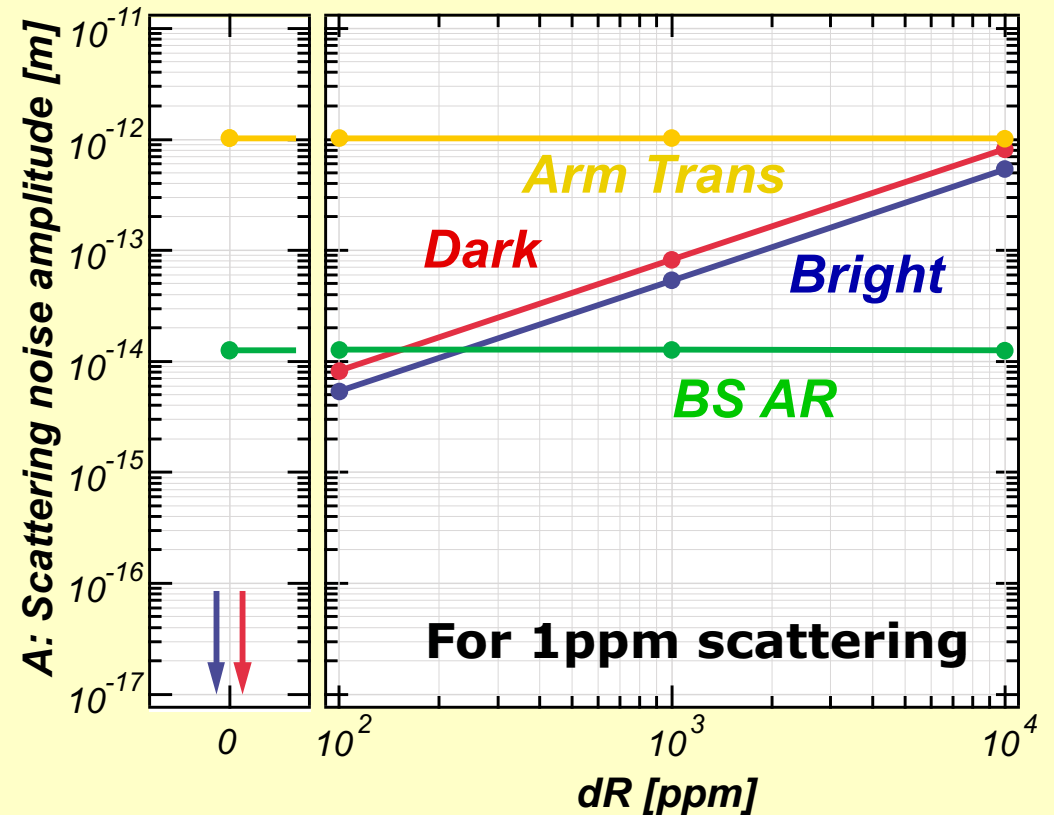
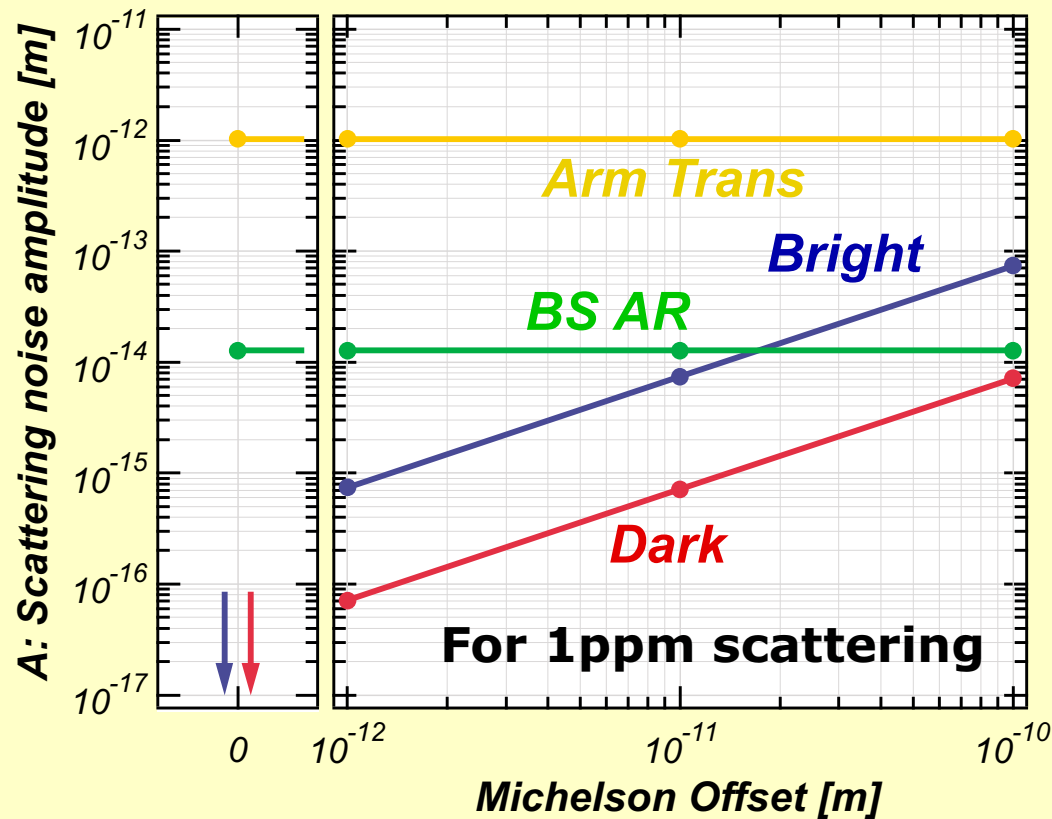
94% is reflected to the bright port

60mWx2 (3%x2) transmitted from the arms



MI case: Change RM with $R=0$

MI model \sim Result



Arm trans. / BS AR noise level: not affected by the deviations

Carrier added to only one of the arm => becomes the signal directly

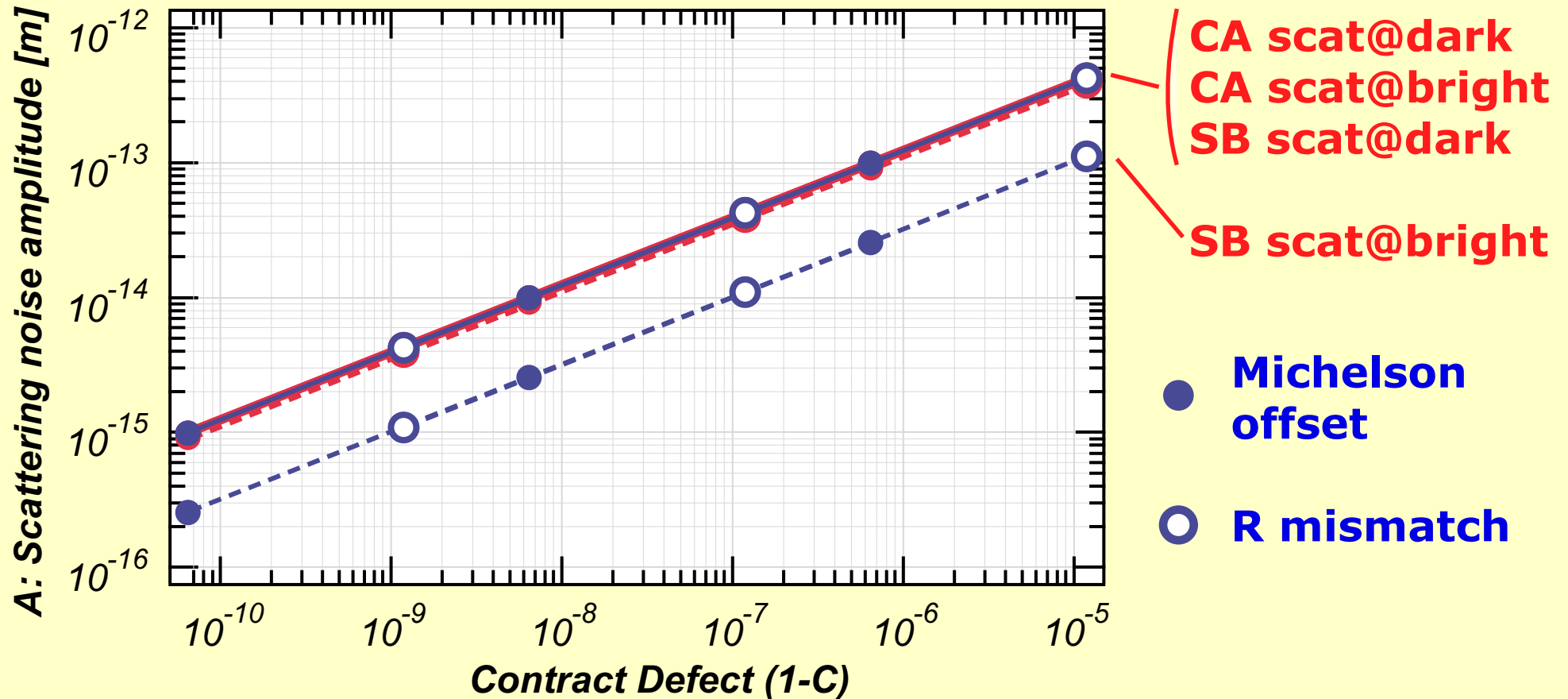
$$A = 9.0 \times 10^{-11} P_{\text{out}} [m] \quad (\text{for 1ppm scattering})$$

Bright/Dark case: depends on how much the imperfection is

Ideal case: no noise \leq No carrier at dark, perfect common mode rejection

MI model \sim Result

- Separate the contrib. of CA and SB



No matter what the origin of the leakage carrier is

**\sim Noise coupling is determined by sqrt of contrast defect
(= by the leakage carrier field at the dark)**

MI model ~ Interpretation

- Noise coupling is determined
by the leakage carrier at the dark

Leakage carrier field $\sqrt{P_{ca@dark}}$

Carrier scattering at the dark port:

All of the injected carrier from the dark port becomes the noise

=> Noise coupling is proportional to $\sqrt{P_{ca@dark}}$

Carrier scattering at the bright port:

How much the carrier does leak to the dark port

=> proportional to $\sqrt{P_{ca@dark}}$

Sideband scattering at the dark port/the bright port:

Some amount of the scattered sidebands appears at the dark port

=> Couples with the leakage carrier

=> Proportional to $\sqrt{P_{ca@dark}}$

MI/RMI model \sim DC power

RMI case:

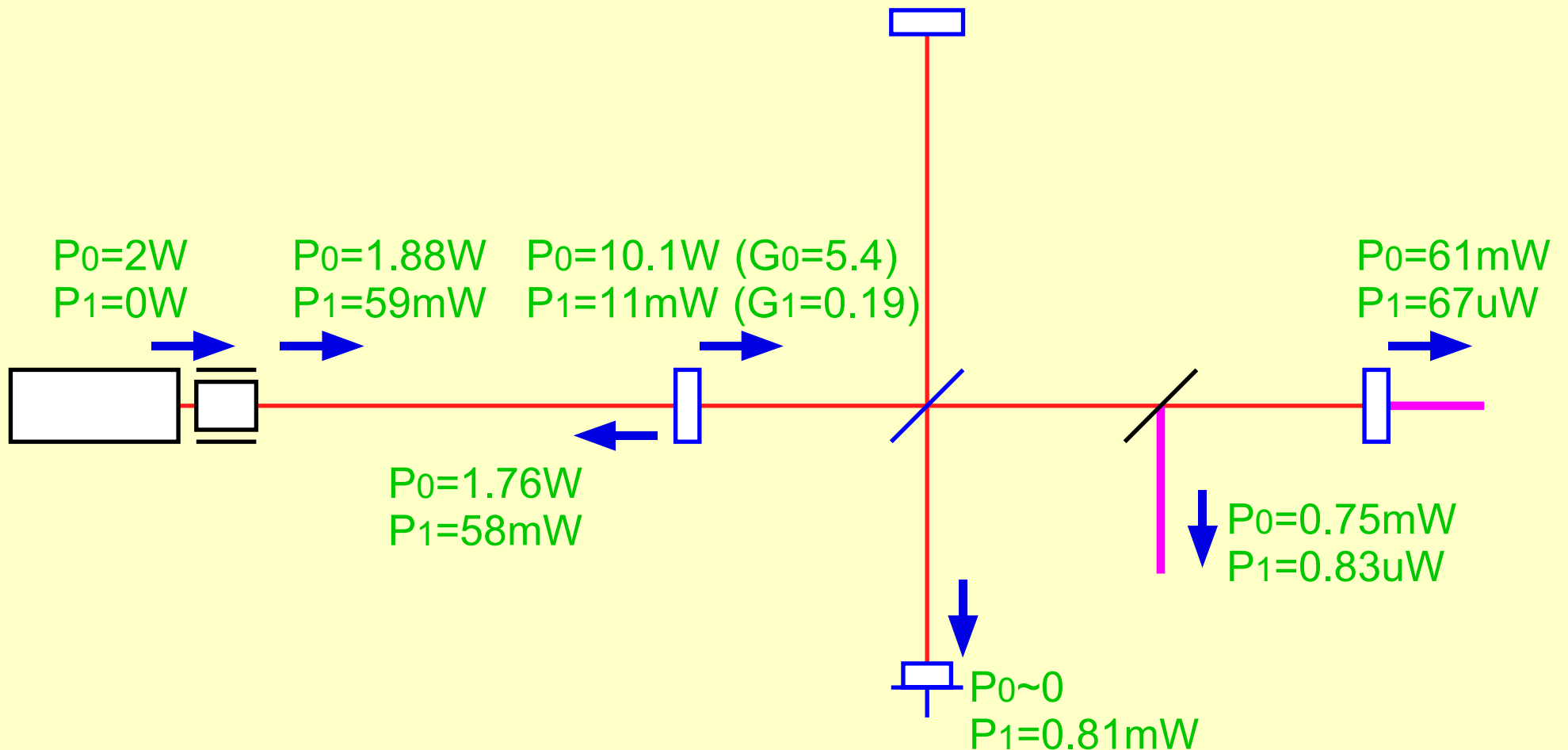
P_0 : carrier power

P_1 : sideband power

Power consumption:

94% is reflected to the bright port

60mWx2 (3%x2) transmitted from the arms



MI case: Change RM with $R=0$

MI/RMI model ~ RMI Result

- Power recycling does not change the situation

Power recycling increases

the scattered light and the signal at the same rate

	MI	(unit: m)	RMI	(unit: m)
Arm Trans	1.02×10^{-12}		1.02×10^{-12}	
BS AR	1.26×10^{-14}		1.26×10^{-14}	
CA scat @ dark	$1.16 \times 10^{-10} \sqrt{1-C}$		$1.20 \times 10^{-10} \sqrt{1-C}$	
SB scat @ dark	$1.07 \times 10^{-10} \sqrt{1-C}$		$1.14 \times 10^{-10} \sqrt{1-C}$	
CA scat @ bright	$1.16 \times 10^{-10} \sqrt{1-C}$		$1.16 \times 10^{-10} \sqrt{1-C}$	
SB scat @ bright	$2.98 \times 10^{-11} \sqrt{1-C}$		$3.39 \times 10^{-11} \sqrt{1-C}$	

MI/RMI model ~ Result Summary

- Asymmetric scattered light

Constant noise coupling

~ Independent from the interferometer condition

$$A = 9.0 \times 10^{-11} P_{\text{out}} [m] \quad (\text{for 1ppm scattering})$$

- Scattering at the dark port and the bright port

Dependent on the contrast defect

$$A \sim 1 \times 10^{-10} \sqrt{1-C} [m] \quad (\text{for 1ppm scattering})$$

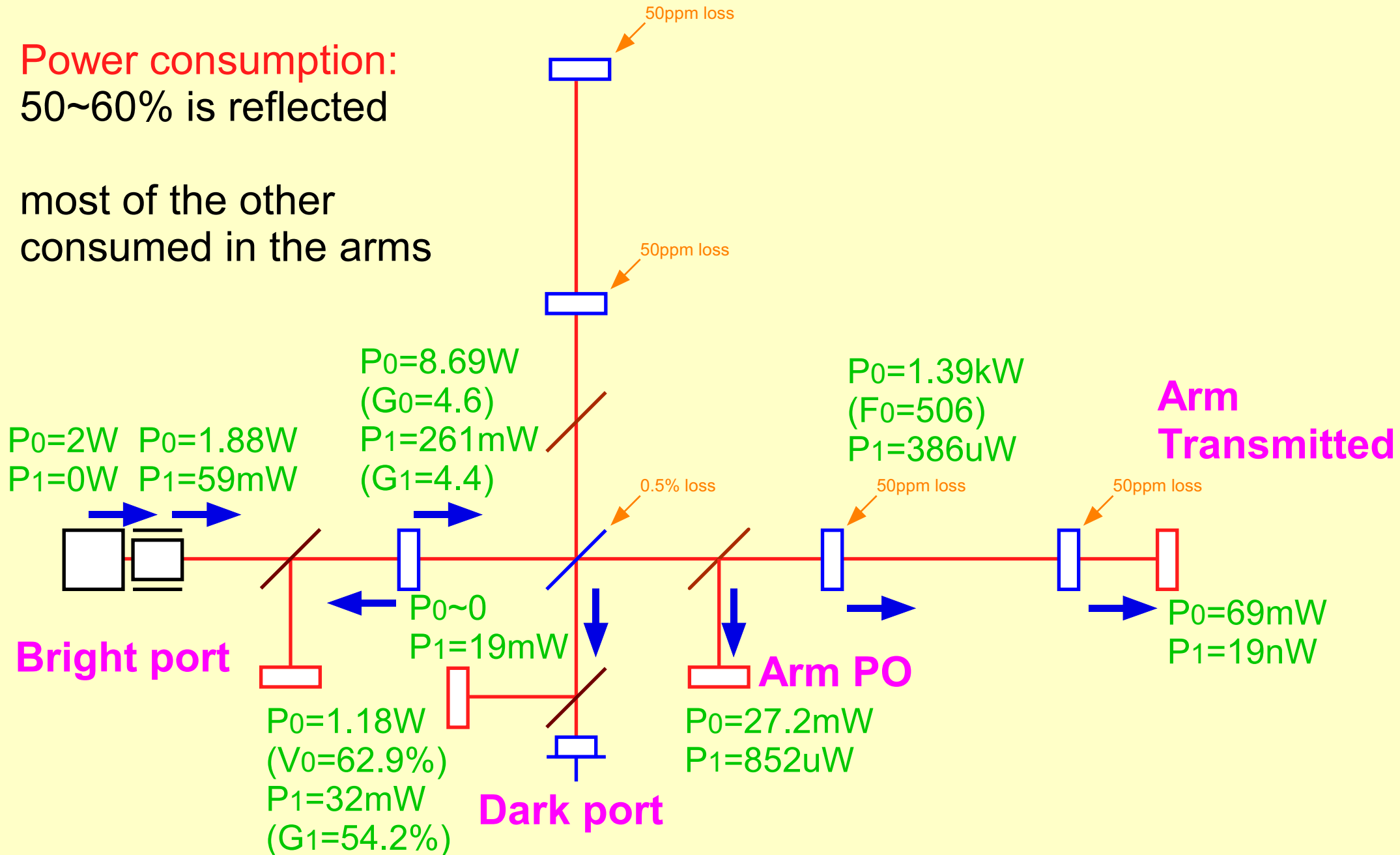
c.f. Bright port ~ Carrier of 2W => Same order contribution
Dark port ~ Carrier of ~0W

- Power recycling does not change
the scattered light noise level

RFPMI model ~ DC light level

Power consumption:
50~60% is reflected

most of the other
consumed in the arms



RFPMI model ~ Result

- Even with the FP arms the noise coupling is understood as the Michelson case **by including the signal enhancement by the FP arm** (factor of $N_{FP}=322$)

	MI	(unit: m)	RFPMI	(unit: m)
FP Arm Trans			4.23×10^{-15}	
BS AR (Arm PO)	$9.0 \times 10^{-11} P_{out}$		$9.0 \times 10^{-11} P_{out} / G_0 / N_{FP}$	
CA scat @ dark	$1.16 \times 10^{-10} \sqrt{(1-C)}$		$1.11 \times 10^{-10} \sqrt{(1-C)}$	
SB scat @ dark	$1.07 \times 10^{-10} \sqrt{(1-C)}$		$0.89 \times 10^{-10} \sqrt{(1-C)}$	
CA scat @ bright	$1.16 \times 10^{-10} \sqrt{(1-C)}$		$0.91 \times 10^{-10} \sqrt{(1-C)}$	
SB scat @ bright	$2.98 \times 10^{-11} \sqrt{(1-C)}$		$2.78 \times 10^{-11} \sqrt{(1-C)}$	

This means:

Scattered light noise level with MI or RMI will appear in the RFPMI sensitivity by a factor of $1/N_{FP}$

Discussion

- Calculation shows:

Noise from the dark port vs Noise from the bright port

=> Comparable

Presence of higher order modes

=> Higher order modes increase the scattered light couples to the main beam

The noise from bright port is not affected

by the higher order modes

=> It may be possible to estimate the imperfection level of the interferometer using the bright port

Conclusion

- Single mode simulation for scattered light noise
MI/RMI/RFPMI cases are essentially the same

=> Considering:

Recycling gain & Signal enhancement by the FP arm

Asymmetric scattered light has the constant contrib.

=> Independent from the interferometer condition

=> Dependent how much power appear at the optical port

Dark port and bright port

=> Dependent on the contrast defect

Presence of higher order modes

=> Increase the noise from the scattering at the dark port